



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

to the application of:

John M. de Larios

Application No. 10/608,871

Filed: June 27, 2003

For: METHOD AND APPARATUS FOR REMOVING
A TARGET LAYER FROM A SUBSTRATE USING
REACTIVE GASES

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Group Art Unit: 1746
)
Examiner: Unassigned
)
Atty. Docket No. LAM2P422
)
Date: January 7, 2004

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on January 7, 2004.

Signed: _____

Sylvia Castillo

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§ 1.56 and 1.97. The Examiner is requested to consider these references and to acknowledge such consideration by initialing the appropriate location on the attached PTO Form 1449.

This Information Disclosure Statement (IDS) is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This IDS is believed to be filed before the mailing date of a first Office Action. Accordingly, it is believed that no fees are due in connection with the filing of this IDS. However, if it is determined that any fees are due, then the Commissioner is hereby authorized to charge such fees to Deposit Account 50-0805 (Order No. LAM2P422).

Respectfully submitted,
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Form 1449 (Modified)  Information Disclosure Statement By Applicant <small>(Use Several Sheets if Necessary)</small>		Attorney Docket No: U.S. LAM2P422 Applicant: John M. de Larios Filing Date: June 27, 2003 Group: 1746
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A	5,464,480	11/7/95	Matthews	134	1.3
	B	6,267,125 B1	7/31/01	Bergman et al.	134	102.1
	C	5,858,283	1/12/99	Burris	261	122.1
	D	3,978,176	8/31/76	Voegeli	261	122
	E	6,276,459 B1	8/21/01	Herrick et al.	169	14
	F	5,900,191	5/4/99	Gray et al.	261	59
	G					
	H					
	I					
	J					
	K					

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	L							
	M							
	N							
	O							
	P							

Other Documents

Examiner Initial	No.	Author, Title, Place (e.g. Journal) of Publication, Date
	R	DENIS WEAIRE ET AL., "The Physics of Foams," Department of Physics Trinity College, Dublin, 1999
	S	BRIAN KIRKPATRICK ET AL., "Advanced Wafer-Cleaning Evolution," Solid State Technology, May 2003
	T	ROBERT J. HUNTER, "Introduction to Modern Colloid Science," Oxford University Press, February 1994
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered.
 Include copy of this form with next communication to applicant.